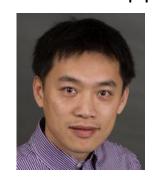


WEBINAR ANNOUNCEMENT

Photolithography at GT-IEN: An Overview of Processes and Equipment

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Date: May 14, 2020

Time: 11:00 AM - 12:00 PM (EDT)

Abstract: Photolithography has always been the most important technique in microelectronics fabrication. It uses light to transfer a geometric pattern from a photomask (also called an optical mask) to a photosensitive (that is, light-sensitive) chemical photoresist on the substrate, or it can be directly written with a UV-laser equipment. It provides precise control of the shape and size of the objects it creates and can create patterns over an entire surface cost-effectively. The Georgia Tech Institute for Electronics and Nanotechnology (IEN) cleanroom provides various types of photolithography equipment to satisfy different processing needs. Each tool has its own unique characteristics and serves different purposes. In this seminar, a brief introduction to the equipment and patterning capabilities of the IEN will be presented. Common processing issues related to photolithography will also be discussed.

Bio: Dr. Hang Chen received his bachelor and master degrees in chemistry from Fudan University in Shanghai, China. He obtained his doctorate, also in chemistry, from Georgia Tech in 2005 and was a post-doc at the Nanotechnology Research Center before joining the IEN as a Research Scientist in 2008. Currently, he is the process support manager at IEN. His research interests include chemically sensitive field-effect transistors, MEMS-CMOS device integration, and organic electronics.

Who should attend: Faculty, scientists, engineers, researchers, and technical staff from university, company, or government labs who use, or are interested in learning about, micro- and nano-scale fabrication and characterization as part of their research efforts.

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